

ok to  
cancel  
4/1/05



AF

Atty. Dkt. No. 025311-0105

**UNITED STATES PATENT AND TRADEMARK OFFICE**

**Applicant:** Ichiro OKABE et al.

**Title:** METHOD OF FORMING A FINE PATTERN, AND METHOD OF  
MANUFACTURING A SEMICONDUCTOR DEVICE, AND A  
SEMICONDUCTOR DEVICE HAVING A FINE PATTERN

**Appl. No.:** 09/597,161

**Filing Date:** 06/20/2000

**Examiner:** Jose R. Diaz

**Art Unit:** 2815

**AMENDMENT AND REPLY UNDER 37 CFR 1.116**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Final Office Action dated May 18, 2005,  
concerning the above-referenced patent application.

**Amendments to the Claims** are reflected in the listing of claims which begins on  
page 2 of this document.

**Remarks/Arguments** begin on page 4 of this document.

Please amend the application as follows: